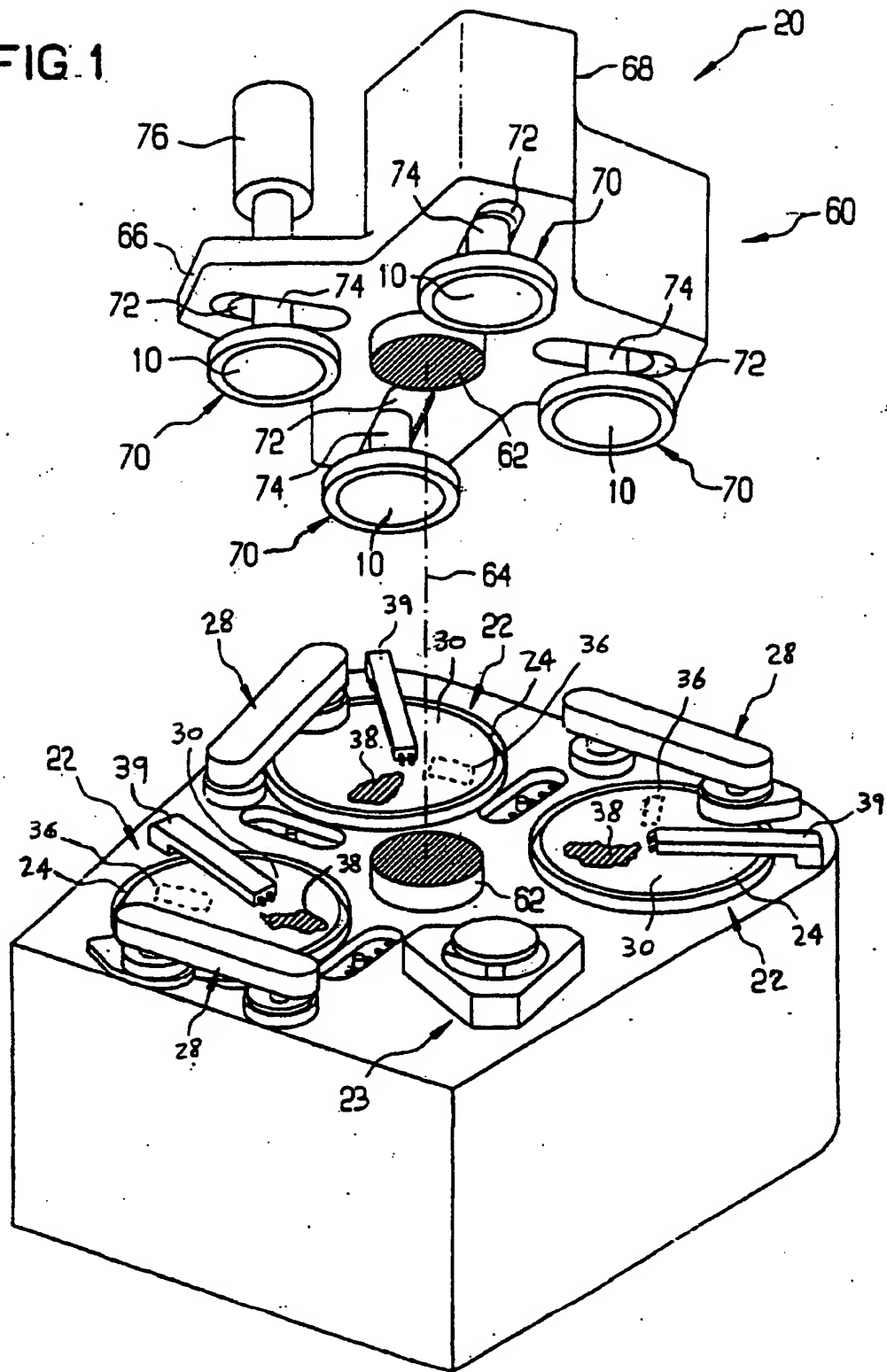
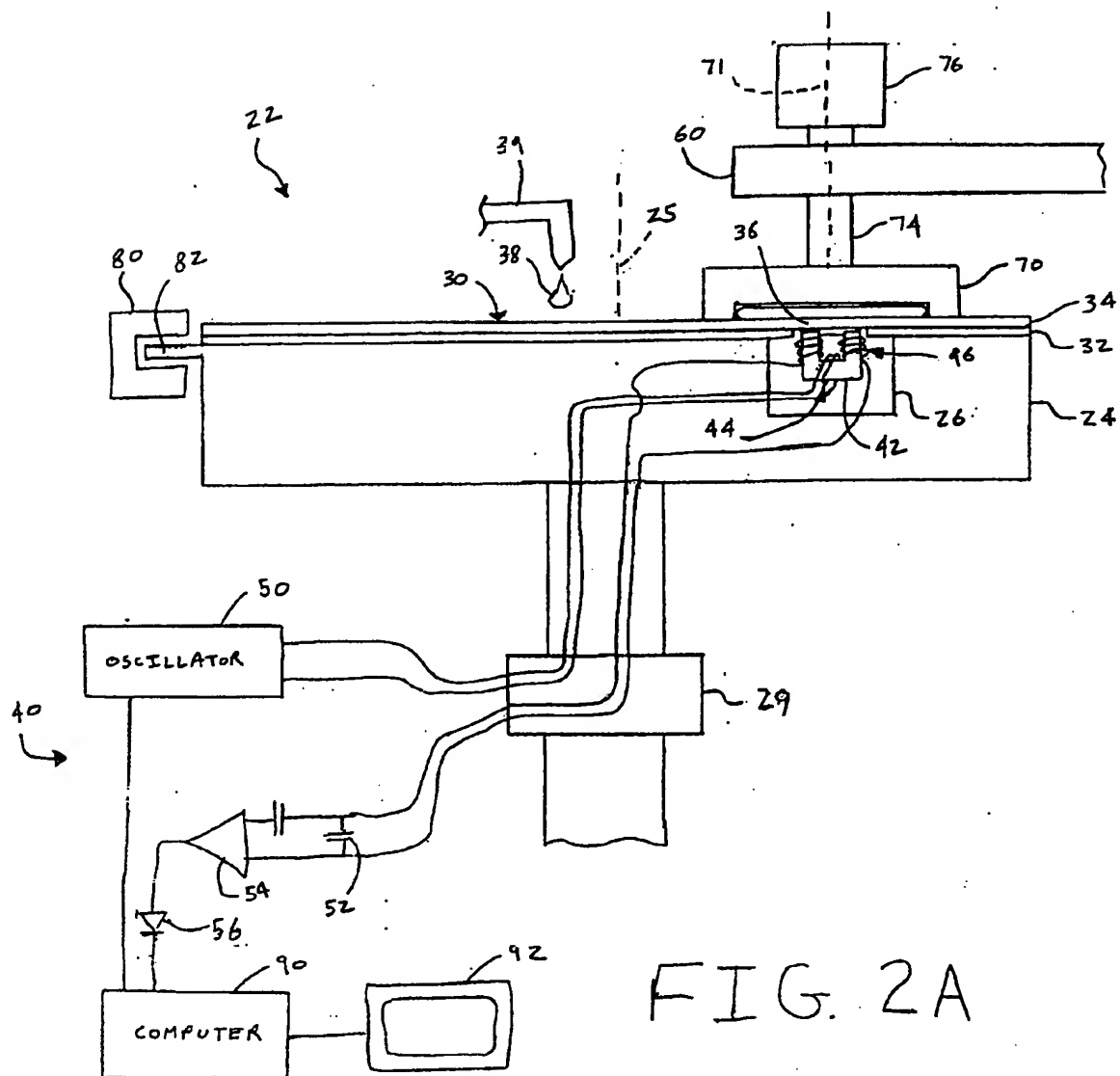


FIG. 1





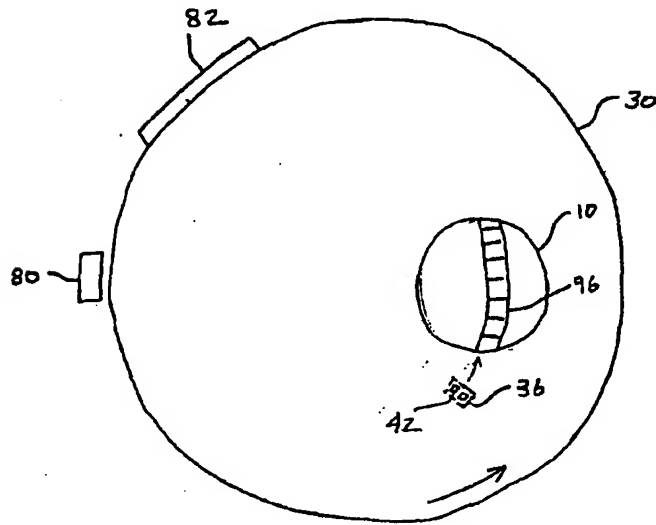


FIG. 2B

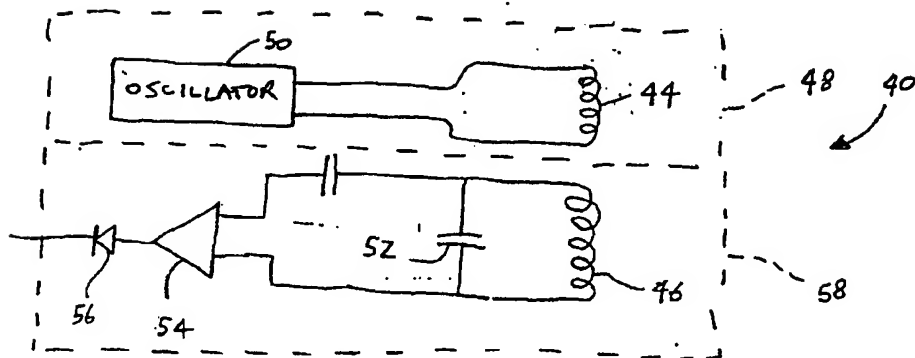


FIG. 3

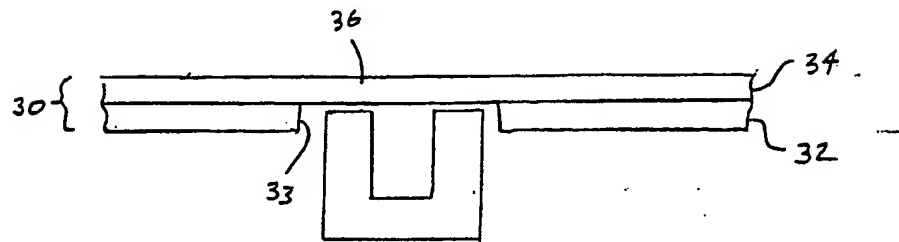


FIG. 4A

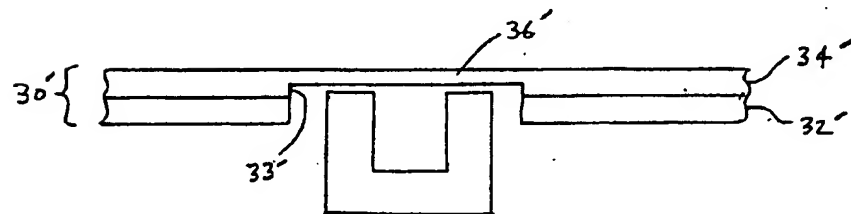


FIG. 4B

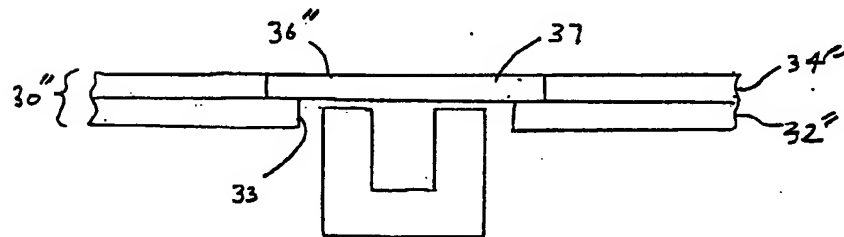


FIG. 4C

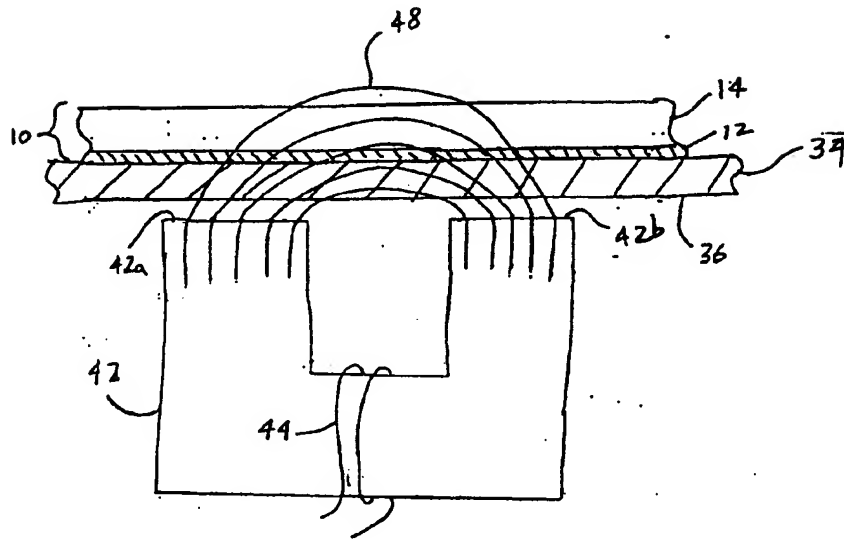


FIG. 5

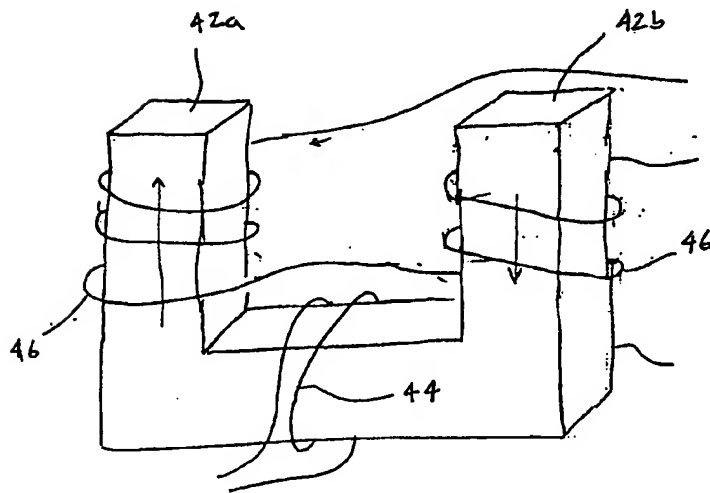


FIG. 6

FIG. 7A

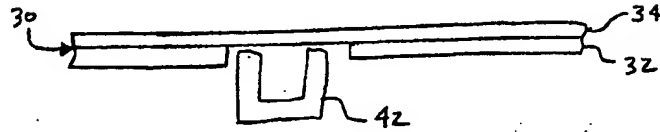


FIG. 7B

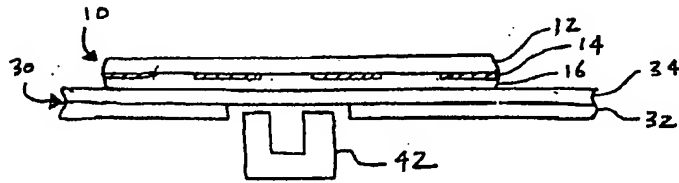


FIG. 7C

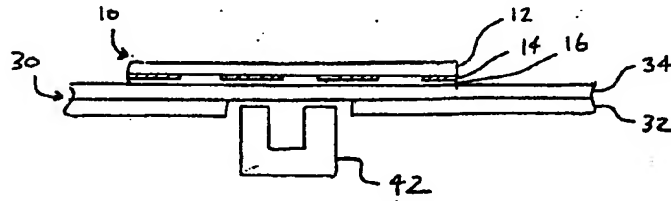
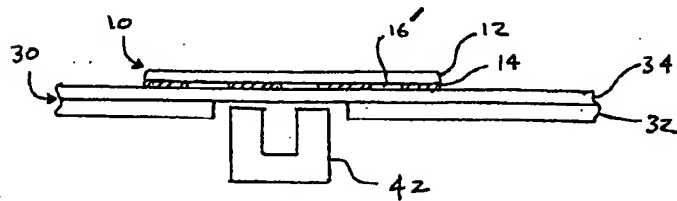


FIG. 7D



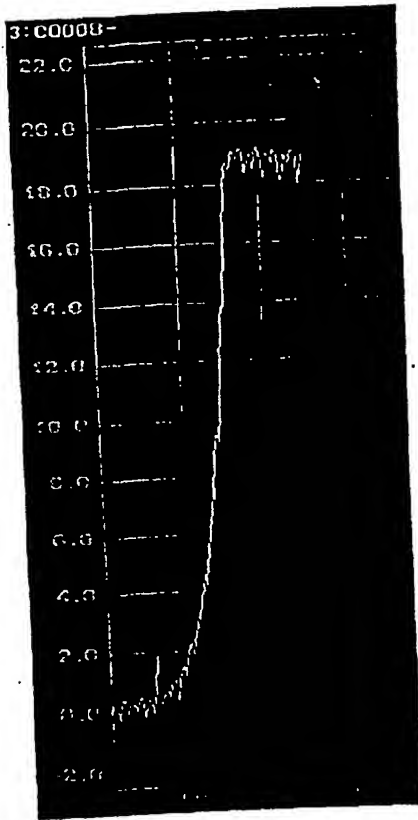


FIG. 8

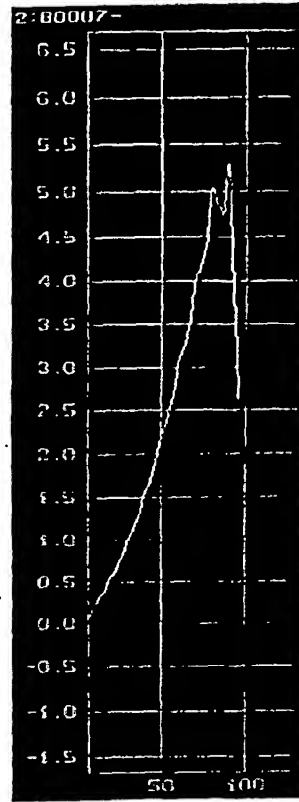


FIG. 11

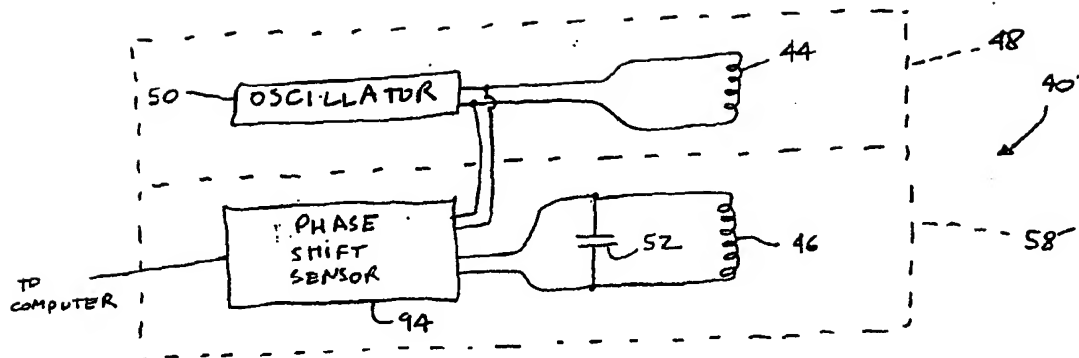
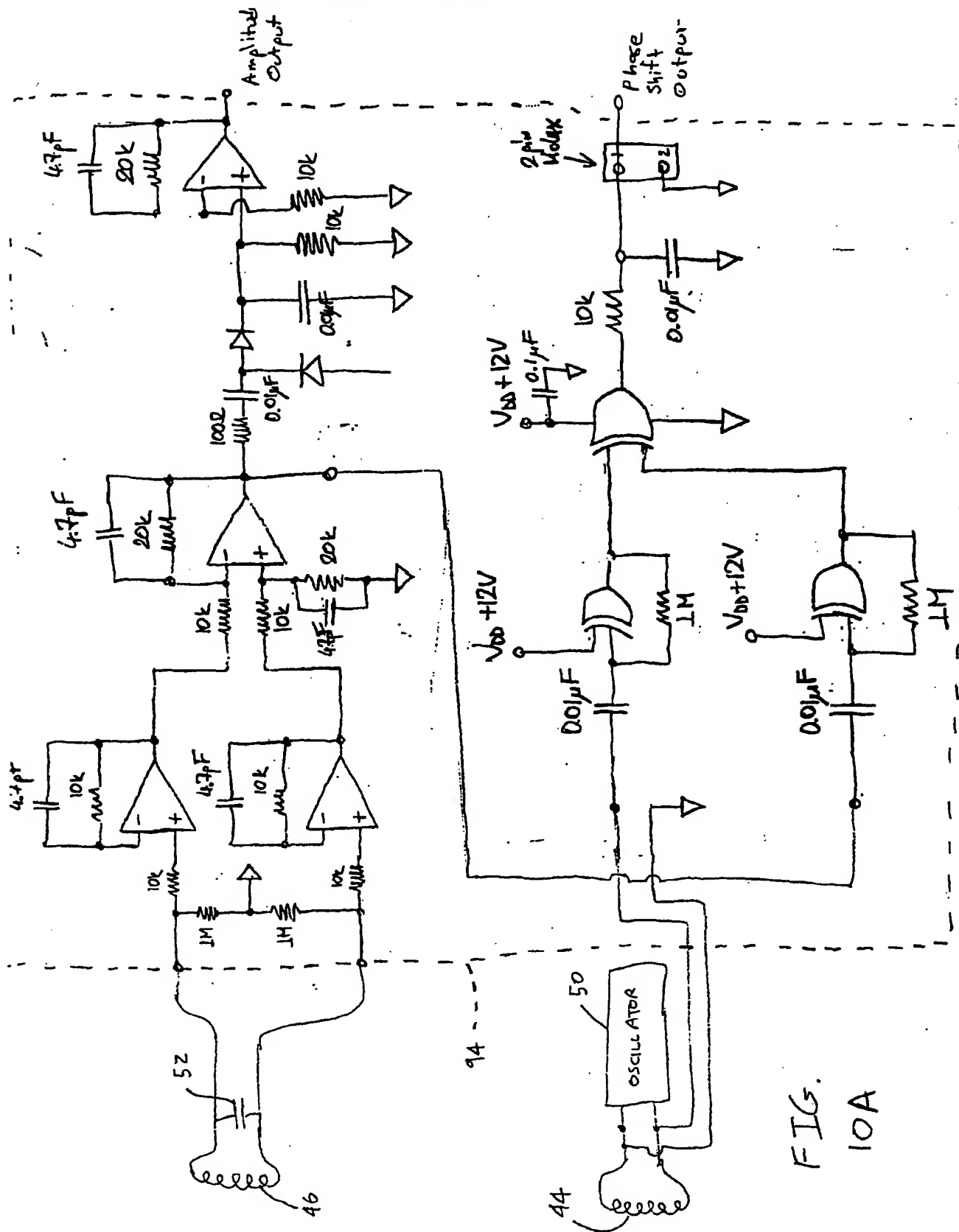


FIG. 9





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CHEMICAL MECHANICAL POLISHING APPARATUS WITH  
NON-CONDUCTIVE ELEMENTS

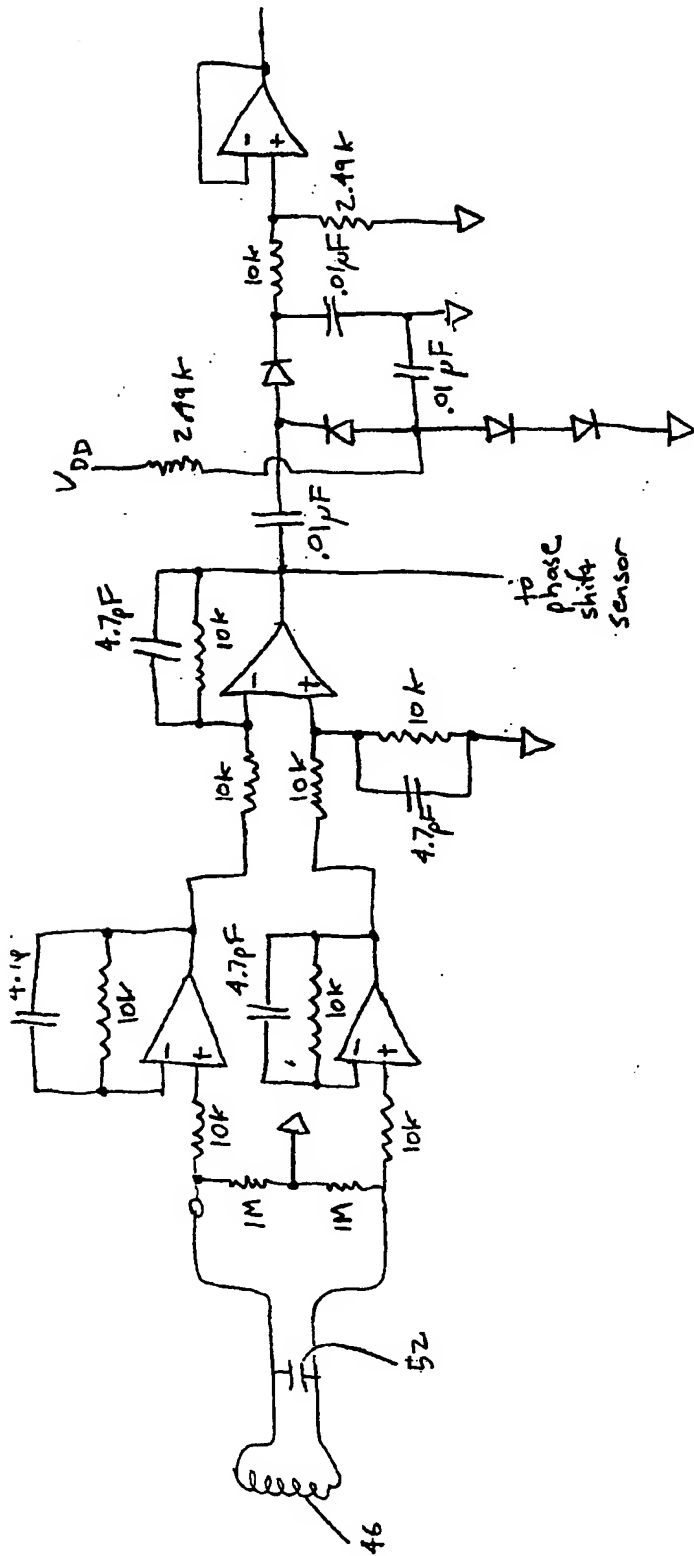


FIG. 10B

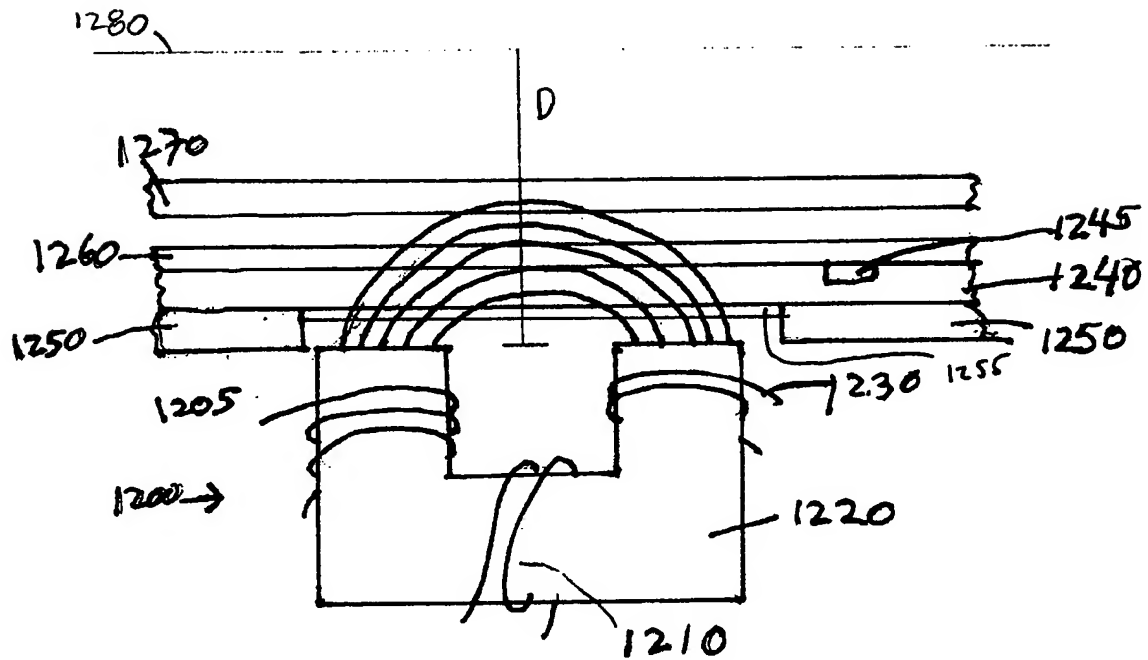


FIG 12

Applicants: Doyle E. Bennett et al.

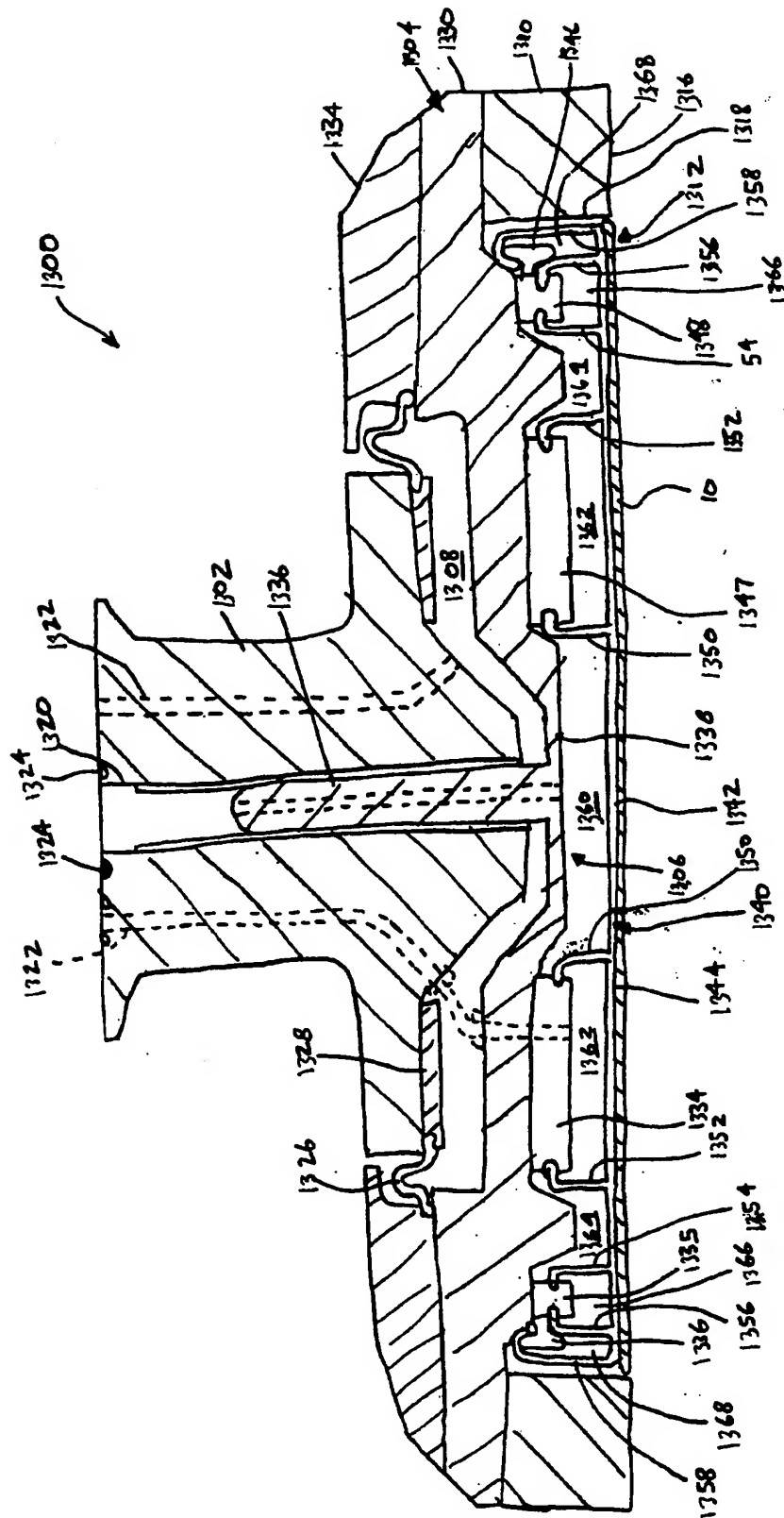
CHEMICAL MECHANICAL POLISHING APPARATUS WITH  
NON-CONDUCTIVE ELEMENTS

FIG. 13

Applicants: Doyle E. Bennett et al.

CHEMICAL MECHANICAL POLISHING APPARATUS WITH  
NON-CONDUCTIVE ELEMENTS

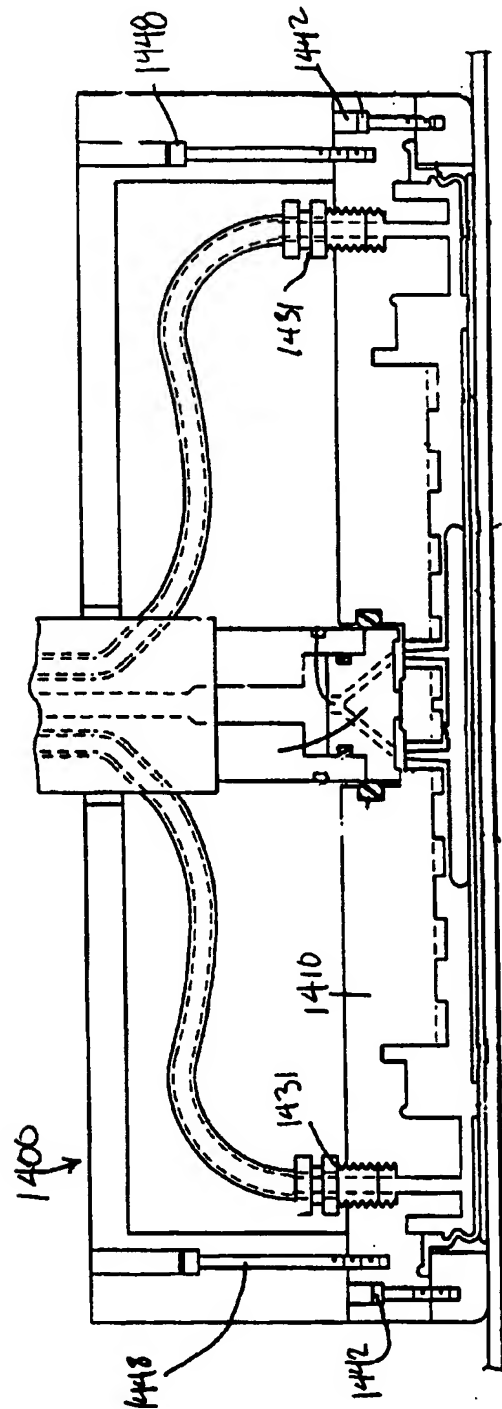
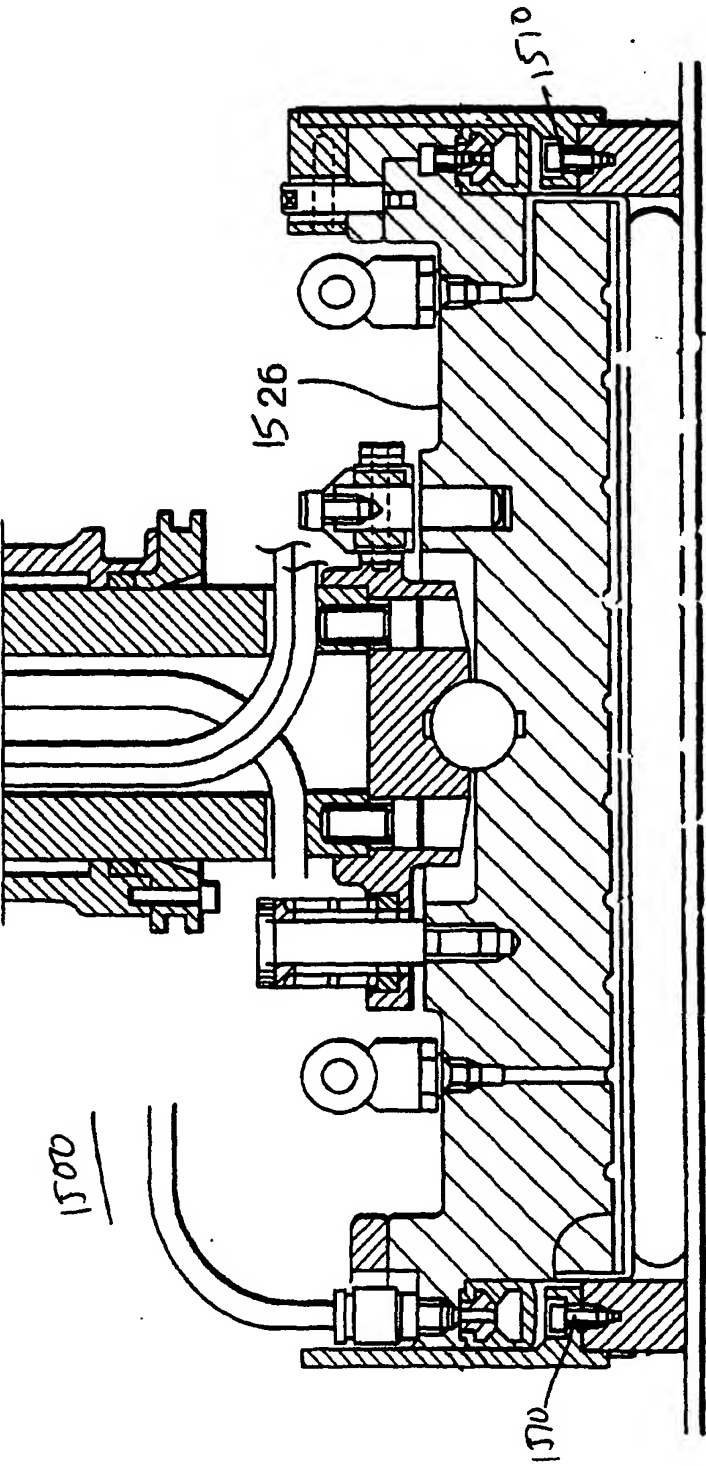


FIG. 14

Fig. 15



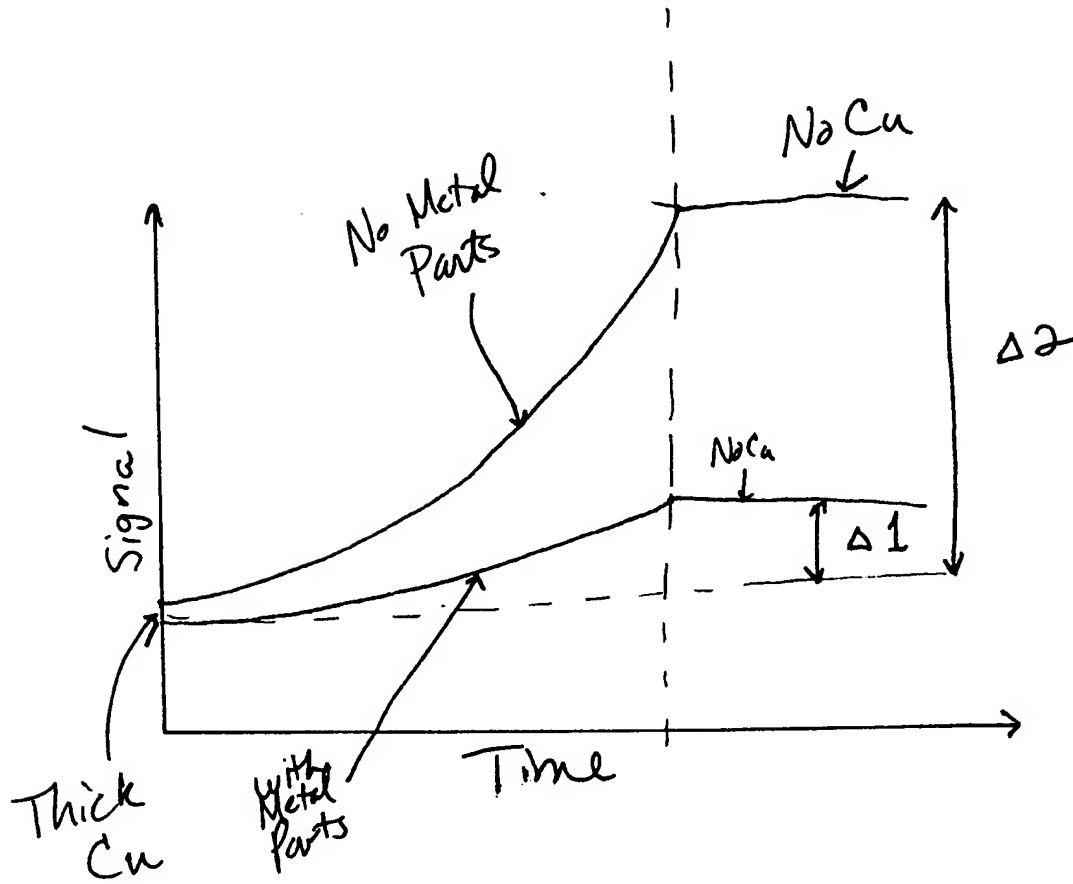


FIG. 16